IG5C Caesium Ion Gun



The IG5C features a low power, high brightness, surface ionisation source coupled to a compact ion column, providing high performance in a small package. The gun is designed as a primary ion beam for all SIMS applications, dynamic, static and imaging.

Controlled via a windows PC based interface, which handles thermal management of the source, the gun is easy and reproducible to set up and can be configured for high current or small spot applications. Drivers for LabView are also available to permit OEM integration into other systems.

Features:

- Air stable ion source
- Small mounting flange for flexible installation
- Easy installation of self aligning replacement sources
- Long source lifetime
- Differential pumping to maintain true UHV chamber pressure
- Two lens column design
- Easy replacement of beam defining aperture

Specification:

Energy: 500 eV to 5 keV Maximum Current: 200 nA Minimum Spot Size: 20 μ m Source Lifetime: typically 500 hours Mounting Flange: Conflat type DN-35-CF Source Power: 8 W

Manufactured in England by:



HIDEN ANALYTICAL LTD. 420 EUROPA BOULEVARD, WARRINGTON, WA5 7UN, ENGLANDTel: +44 (0)1925 445225Fax: +44 (0)1925 416518Email: info@hiden.co.uk



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IG20 Oxygen / Gas Gun

The IG20 features a high brightness electron impact gas ion source which is designed specifically for oxygen capability but is also suitable for use with inert and other gases. The IG20 is designed as primary ion beam for SIMS, Auger and XPS applications for imaging and depth profiling, however, the internally generated raster scan and wide range of operating parameters make it suitable for sample cleaning and surface science experiments. Twin user switchable filaments ensure continued operation in the case of a blown filament – which may be replaced at the user's

The gun is easy and reproducible to set-up using a Windows PC based interface and the supplied program. Drivers for LabView are also available to permit OEM integration into other systems.



convenience.

Features:

• High current density

Neutral dump

- Oxygen compatible
- Differential pumping
- Easily replaceable twin filaments
- Small mounting flange for flexible installation
- Bakeable to 200 °C

Specification:

Energy: 500 eV to 5 keVMaximum Current: 800 nAMinimum Spot Size: 50 μ mFilament Lifetime: >1000 hoursMounting Flange: Conflat DN-35-CFSource Gas Pressure: 0.1 to 0.5 bar above atmosphere

Manufactured in England by:



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